FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. TOPTICS.018A	APPLICATION NO. 09/891,689
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	APPLICANT Gene H. Haertling	
	FILING DATE June 26, 2001	GROUP 2873

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
EH		6,288,822	09/11/01	Romanovsky	359	245	
EH		6,297,899	10/02/01	Romanovsky	359	245	
EH		6,486,996	11/26/02	Romanovsky	359	245	
EH		6,614,574	09/02/03	Romanovsky	359	247	
EH		2002/0181067	12/05/02	Romanovsky, et al. (SN 10/013336)	359	245	

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO

EXAMINER INITIAL		OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)

H:\DOCS\MJG\MJG-6375.DOC:ad
063004

EXAMINER EH Lester	DATE CONSIDERED 4-13-05

*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. TOPTICS.018A	APPLICATION NO. 09/891,689
	APPLICANT Gene H. Haertling	
	FILING DATE June 26, 2001	GROUP 2873

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
EAH	1.	4,201,442	05/1980	McMahon et al.	385	17	
EAH	2.	4,796,982	01/1989	Kitabatake et al.	359	318	
EAH	3.	4,993,811	02/19/91	Blazey et al.	359	251	
EAH	4.	5,011,271	04/30/91	Saito et al.	359	359	
EAH	5.	5,016,959	05/1991	Diemeer	385	16	
EAH	6.	5,745,280	4/1998	Kitano	359	290	
EAH	7.	5,369,718	11/1994	Kamata et al.	385	21	
EAH	8.	5,911,018	6/1999	Bischel et al.	385	16	

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO
EAH	9.	0 344 857 A1	05/1989	Europe				

EXAMINER INITIAL		OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
EAH	10.	*Antiferroelectric-Phase PLZT For Use In High Density Optical Data Storage*, S. Mancha, J. Bullington, R. Carter and C. Dehainaut, Airforce Weapons Laboratory (AFSC) Kirtland Airforce Base New Mexico, *Ferroelectrics*, 1988 Gordon and Breach Science Publishers S.A., Vol. 82, pp. 99-104.
EAH	11.	*Crystallization of Lanthanum-Modified Lead Zirconate Titanate (PLZT) Using Coprecipitated Gels*, Yao-Jung Lee, Fu-Su Yen, Jong-Ping Wu and Hsing-I Hsiang, Jpn. J. Appl. Phys., Vol. 34, Pt. 1, No. 8A, August 1995, pp. 4137-4142.
EAH	12.	*Crystallization of Silicon on Electro-Optic PLZT by a Laser Beam Modulated in Shape and Intensity Profile*, T.H. Lin, M.L. Burgener, S.C. Esener and S.H. Lee, Mat. Res. Soc. Symp. Proc., Vol. 74, 1987, pp. 135-140.
EAH	13.	*Dielectric Properties of (111) and (100) Lead-Zirconate-Titanate Films Prepared by Sol-Gel Technique*, K. Aoki et al., Jpn. J. Appl. Phys., Vol. 33 (1994) Pt. 1, No. 9B, pp. 5155-5158.
EAH	14.	*Effects of O3 on Growth and Electrical Properties of Pb(Zr, Ti)O3 Thin Films by Photoenhanced Metalorganic Chemical Vapor Deposition*, Masaru Shimizu et al., Jpn. J. Appl. Phys., Vol. 33 (1994) Pt. 1, No. 9B, pp. 5135-5138.
EAH	15.	*Electric and Optical Properties of PLZT Ceramic Shutter Array*, Y. Takubo et al., Jpn. J. Appl. Phys., Vol. 24 (1985) Supplement 24-3, pp. 159-161.
EAH	16.	*Fabrication of Transparent PLZT Ceramics by Atomsphere Sintering*, Katsuhiko Tanaka et al., Japanese Journal of Applied Physics, Vol. 24 (1985) Supplement 26-3, pp. 107-109.
EAH	17.	*Fabrication of Transparent PLZT Ceramics with a High Transmittance and Their Application to Optical Light Shutter*, Kunihiko Hayashi, et al., Proceedings of the 6th Meeting on Ferroelectric Materials and Their Applications, Kyoto 1987, Japanese Journal of Applied Physics, Vol. 26 (1987) Supplement 26-2, pp. 126-128.
EAH	18.	*High Speed Optical TIR Switches Using PLZT Thin-Film Waveguides on Sapphire*, Hidetaka Higashino, Takao Kawaguchi, Hideaki Adachi, Toshihiko Makino and Osamu Yamazaki, Proceedings of the Sixth International meeting on Ferroelectricity, Kobe, 1985, Jpn. J. Appl. Phys. Vol 24 (1985) Suppl. 24-2, p. 284-286.

EXAMINER	DATE CONSIDERED 4-13-05

*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. TOPTICS.018A	APPLICATION NO. 09/891,689
	APPLICANT Gene H. Haertling	
	FILING DATE June 26, 2001	GROUP 2873

EXAMINER INITIAL		OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
EAH	19.	Optical Switch Utilizing Total Reflection of (Pb, La) (Zr, Ti)O_3 Ceramics, Toshio Utsunomiya, Jpn J. Appl. Phys. Vol. 33 (1994) pp. 5440-5442 Part 1, No. 9B, September 1994.
EAH	20.	*Optical TIR Switches Using PLZT Thin-Film Waveguides on Sapphire*, Kiyotaka Wasa et al., Journal of Lightwave Technology, Vol. LT-2, No. 5, pp. 710-713, October 1984.
EAH	21.	*A (Pb, La)(Zr, Ti)O3 (PLZT) Polarization-Plane with a Buried Electrode Structure for a Mid-Infrared Electro-Optical Shutter*, Yoshiharu Taniguchi, Kensuke Murakami, Hiroshi Kobayashi and Shosaku Tanaka, Jpn. J. Appl. Phys., Vol. 36 (1997) Pt. 1, No. 5A, pp. 2709-2714.
EAH	22.	*PLZT Electrooptic Shutter*, K. Tanaka et al., Jpn. J. Appl. Phys., Vol. 22 (1983) Supplement 22-2, pp. 126-128.
EAH	23.	*The Polarization-Reversal Characteristics of Pb(Zr, Ti)O_3 Family Ceramics*, Y. Masuda et al., Proceedings of the 4th Meeting on Ferroelectric Materials and Their Applications, Kyoto 1983, Jpn. J. Appl. Phys., Vol. 22 (1983) Supplement 22-2, pp. 118-122.
EAH	24.	*Preparation and Characterization of Sol-Gel Derived Epitaxial and Oriented Pb($Zr_{0.52}$ $Ti_{0.48}$)O_3 Thin Films*, Keiichi Nashimoto and Shigetoshi Nakamura, Jpn. J. Appl. Phys., Vol. 33 (1994) Pt. 1, No. 9B, pp. 5147-5150.
EAH	25.	*Preparation of Pb(Zr,Ti)O_3 Thin Films by Sol-Gel Technique*, Tomoyasu Takusagawa, Noriaki Yamada, Terumasa Kato, Hajime Hattori and Teruyuki Matsui, Jpn. J. Appl. Phys. Vol. 33, Pt. 1, No. 9B, 1994, pp. 5151-5154.
EAH	26.	*Prism-Type Optical Deflector Using PLZT Ceramics*, Toshio Utsunomiya et al., Japanese Journal of Applied Physics, Vol. 24, (1985) Supplement 24-3, pp. 169-171.
EAH	27.	*Uniform Ultra-Thin Pb(Zr, Ti)O3 Films Formed by Metal-Organic Chemical Vapor Deposition and Their Electrical Characteristics*, Hiroshi Miki and Yuzuru Ohji, Jpn. J. Appl. Phys., Vol. 33 (1994) Pt. 1, No. 9B, pp. 5143-5146.
	~~28.~~	~~(Co-pending) U.S. Patent Application No. 10/040,336 (Attorney Docket No. TOPTICS.004CP2)~~ See US PG PUB 2002/0181067 already listed

H:\DOCS\ADB\ADB-1657.DOC
083104

EXAMINER EAH	DATE CONSIDERED 4-13-05

*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.